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PATENT & TRADEMARK OFFICE

Sheet 1 of 1

Form PTO-1449 (REV. 8-83)			US Dept. of Commerce PATENT & TRADEMARK OFFICE			ATTY DOCKET NO. 107291	APPLICATION NO. 09/701,534
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)			APPLICANT(S) Shunichi SEKI et al.				
			FILING DATE November 30, 2000			GROUP 1762	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME		CLASS	SUB CLASS
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY		CLASS	SUB CLASS
MBC	1	GB 2 077 710 A	12/23/1981	Great Britain		—	—
MBC	2	JP-A 64-029661 w/ Abstract	01/31/1989	Japan		—	—
MBC	3	JP-A 09-237927 w/ Abstract and translation	09/09/1997	Japan		—	—
MBC	4	JP-A 63-111454 w/ Abstract	05/16/1988	Japan		—	—
MBC	5	JP-A 10-321536 w/ Abstract and translation	12/04/1998	Japan		—	—
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
MBC	6	"Advances in deposition Processes for Passivation Films", W. Kern et al., J. Vac. Sci. Technology, 14, 1082, ©1977.					
MBC	7	"Substitutional doping of Amorphous Silicon", W. E. Spear et al., Solid State Communications, 17, 1193, ©1975.					
EXAMINER					DATE CONSIDERED 9/15/04		
Examiner:	Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.						